

Form 1449 (Modified)			
Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)		Atty Docket No. 01-471/1D / LSI1P172D1	Application No.: Filed Herewith
		Applicant: CATABAY et al.	<i>10/772 133</i>
		Filing Date 2/3/04	Group Unassigned
Herewith			

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
TN	A	5,925,415	07/20/99	Fry et al.	427	304	03/09/98
	B	6,010,962	01/04/00	Liu et al.	438	687	02/12/99
	C	6,015,749	01/18/00	Liu et al.	438	628	05/04/98
	D	6,022,808	02/08/00	Nogami et al.	438	694	03/16/98
	E	6,037,258	03/14/00	Liu et al.	438	687	05/07/99
	F	6,042,889	03/28/00	Ballard et al.	427	305	02/28/94
	G	6,066,892	05/23/00	Ding et al.	257	751	05/14/98
	H	6,162,727	12/19/00	Schonauer et al.	438	687	11/25/98
↓	I	6,235,406	05/22/01	Uzoh	428	620	07/13/00

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J			/				
	K			/				
	L			/				
	M			/				
	N			/				

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
TN	O	Wolfe, et al., Silicon Processing for the VLSI Era, Vol. 1 – Process Technology, 2 nd Ed., Lattice Press: Sunset Beach, CA, 2000, pp. 791-795.
TN	P	U.S. Patent Application No. 10/035,705, "Electroless Deposition of Copper to Form Copper Interconnect Structures", filed 10/18/01.
	Q	

Examiner

T. Nguyen

Date Considered

4/6/06

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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		Group	Unassigned

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
TN	AA	6,255,192B1	07/03/01	Dornisch	438	430	09/09/98
	BB	6,268,291B1	07/31/01	Andricacos et al.	438	694	12/03/98
	CC	6,287,968B1	09/11/01	Yu et al.	438	675	01/04/99
	DD	6,297,158B1	10/02/01	Liu et al.	438	687	05/31/00
	EE	6,328,871B1	12/11/01	Ding et al.	205	183	08/16/99
	FF	6,368,967B1	04/09/02	Besser	438	687	05/04/00
	GG	6,376,370B1	04/23/02	Farrar	438	678	01/18/00
	HH	6,391,777B1	05/21/02	Chen et al.	438	687	05/02/01
W	II	6,429,121B1	08/06/02	Hopper et al.	438	686	02/07/01

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	JJ							
	KK							
	LL							
	MM							
	NN							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	OO	
	PP	
	QQ	
Examiner		Date Considered
	<i>T. Nguyen</i>	<i>4/6/04</i>

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(Use Several Sheets if Necessary)				Filing Date Herewith 2/3/04	Group Unassigned

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
TN	AAA	6,440,849B1	08/27/02	Merchant et al.	438	658	10/18/99
	BBB	6,445,070B1	09/03/02	Wang et al.	257	751	01/29/01
	CCC	6,461,675B2	10/08/02	Paranjpe et al.	427	250	07/10/98
V	DDD	6,465,376B2	10/15/02	Uzoh et al.	438	927	08/18/99
	EEE						
	FFF						
	GGG						
	HHH						
	III						

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							Yes	No
	JJJ							
	KKK							
	LLL							
	MMM							
	NNN							

Other Documents

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	QQQ			
Examiner		Date Considered	4/6/04	

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